

On-Chip Matching Networks for Radio-Frequency Single-Electron-Transistors

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In this letter, we describe operation of a radio-frequency superconducting single electron transistor (RF-SSET) with an on-chip superconducting LC matching network consisting of a spiral inductor L and its capacitance to ground C_p . The superconducting network has a lower C_p and gives a better matching for the RF-SSET than does a commercial chip inductor. Moreover, the superconducting network has negligibly low dissipation, leading to sensitive response to changes in the RF-SSET impedance. The charge sensitivity $\delta q = 2.4 \times 10^{-6} e/\sqrt{\text{Hz}}$ in the sub-gap region and energy sensitivity $\delta \epsilon = 1.9\hbar$ indicate that the RF-SSET is operating in the vicinity of the shot noise limit.

With growing interest in quantum computation,^{1,2} spin-based qubits,^{3,4} the quantum properties of nanomechanical resonators,^{5,6} and quantum measurement^{7,8} much attention has been focused on ultra-fast charge detectors such as the radio-frequency single electron transistor (RF-SET).^{9,10,11,12} In rf mode, the SET is embedded in an LC network as illustrated in Fig. 1(a) allowing a working bandwidth of tens of MHz and avoiding $1/f$ noise from amplifiers and background charges. The LC network usually consists of a commercial chip inductor L and its parasitic capacitance to ground C_p ; such networks, however, have drawbacks such as losses and relatively large C_p that degrade the performance of the SET.

In this letter, we describe RF-SSETs with on-chip fully superconducting LC matching networks. Although our best charge sensitivity $\delta q = 2.4 \times 10^{-6} e/\sqrt{\text{Hz}}$ does not quite match the record to date¹², our SET and matching network design are not yet fully optimized. Furthermore, our measurement is in the sub-gap region for which transport occurs via a combination of Cooper pair and quasiparticle tunneling. The backaction of the SET, the rate at which it dephases a measurement,^{13,14} is predicted to be smaller in the sub-gap region than in the above-gap region for which Coulomb blockade of quasiparticles dominates.^{10,11,12}

Fig. 1(a) shows an idealized model for an on-chip superconducting matching network. One end of the SET is connected to an Al spiral inductor L , which is then connected via a coaxial cable to room temperature electronics. The other end of the SET is grounded directly to the cable shield. The inductor L , the SET differential resistance R_d , and the stray capacitance C_p from the inductor and SET bonding pads to ground form an LCR network with resonant frequency $f_0 \approx \frac{1}{2\pi\sqrt{LC_p}}$. A carrier wave with frequency f_0 and rms amplitude v_{rf} is applied to the network and the reflected signal is measured. The reflection coefficient at resonance is given by $\Gamma = \frac{Z_{\text{in}} - 50}{Z_{\text{in}} + 50}$ where the input impedance of the network $Z_{\text{in}} = \frac{L}{R_d C_p}$. In order to optimize the charge sensitivity, Z_{in} should be impedance matched to the 50Ω coaxial cable at the point of maximal change in SET conductance with charge. The unloaded quality factor $Q = \sqrt{\frac{L}{C_p}} \frac{1}{Z_0}$ determines the amplitude of the rf signal applied to the SET $v_{\text{SET}} = 2Qv_{\text{rf}}$ and the resonance bandwidth f_0/Q .

An on-chip superconducting matching network has three advantages in comparison with a commercial chip inductor. First, because C_p is smaller for an on-chip network, better impedance matching can be attained at higher frequencies, resulting in a larger resonance bandwidth for a given Q . Second, an on-chip network can be extended to multi-pole matching networks¹⁵ that can further increase the bandwidth, possibly allowing measurements on nanosecond time scales. Finally, our on-chip LC networks are entirely superconducting at our

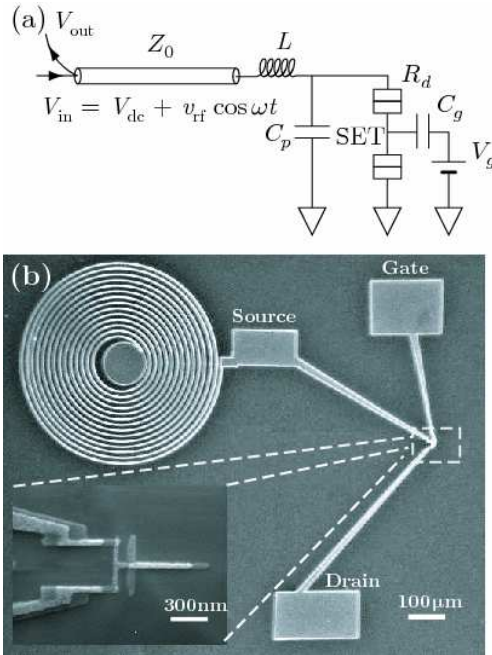


FIG. 1: (a) Idealized model of an LC matching network. (b) Optical micrograph of an on-chip matching network prior to wire bonding. The apparent inductor linewidth is set by the resolution of the image. The inset shows an electron micrograph of the SET.

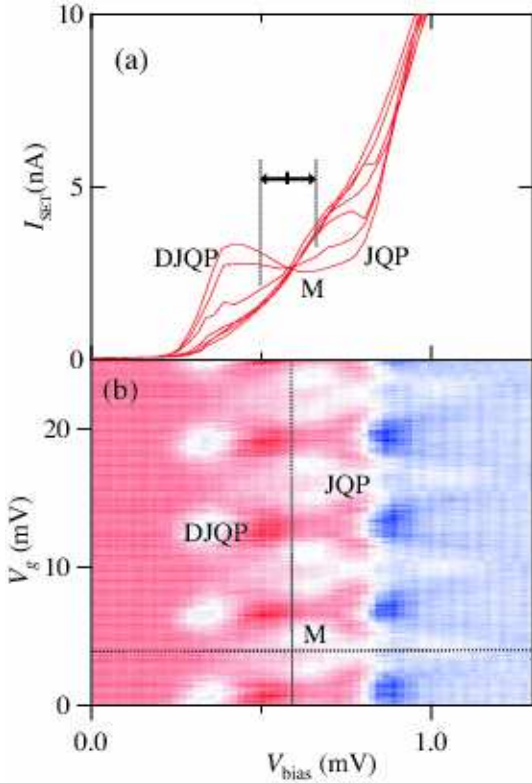


FIG. 2: (a) I - V curves of sample A for various V_g . The modulation at the DJQP and JQP features is about 2 nA. Point M shows the dc bias V_{dc} for optimal RF-SET operation and the arrows and vertical dashed lines show the peak rf amplitude at the SET $v_{SET} = 2Qv_{rf} \approx 160 \mu V$. (b) False-color image of G_d versus V_{dc} and V_g . Experimentally determined optimal values of V_{dc} and V_g for rf operation are indicated by the dashed lines.

measurement temperature and have negligible loss at radio frequencies. In comparison, the input impedance at resonance of a matching network that includes normal metals has loss terms arising from dissipation in the inductor L or capacitor C_p in addition to the transformed SET impedance $\frac{L}{R_d C_p}$. The reflection coefficient for a lossy network is therefore less sensitive to changes in R_d . While fully on-chip matching networks have been used previously, they have generally included some normal metal components.^{6,16}

Fig. 1(b) shows an optical micrograph of an on-chip network. The network is fabricated together with the SET by e-beam lithography and double-angle shadow evaporation of Al. The number and spacing of the turns of the spiral inductor (linewidth $3 \mu m$, line spacing $20 \mu m$) determines L . The inset of Fig. 1(b) shows a scanning electron micrograph of the SET with junction area about $40 \times 60 \text{ nm}^2$. The center of the spiral inductor is wire bonded using an Al wire to the central pin of a coaxial cable and the ground lead of the SET is similarly bonded to the cable shield.

The measurements were carried out in a ^3He refrigera-

tor at the base temperature of 290 mK. Copper-stainless steel powder filters in the cryostat and π -type filters at room temperature were used to eliminate high frequency noise. A low-noise HEMT amplifier and directional coupler were located in the cryostat at a temperature of around 2.8 K. We made two samples with the same SET design and similar total normal-state resistance R_n : sample A was coupled to a 12-turn spiral inductor and sample B to a 14-turn inductor. DC I - V curves were measured with custom-made low noise current and voltage amplifiers, and the SET differential conductance $G_d = 1/R_d$ via standard lock-in techniques. Results for sample A are shown in Fig. 2. Features associated with two sub-gap charge transport cycles, the Josephson-quasiparticle (JQP) and double Josephson-quasiparticle (DJQP) cycles are clearly visible; for a detailed discussion see Ref. 17 and references therein. We determined the SET charging energy $E_c = e^2/2C_\Sigma = 205 \mu eV$ where C_Σ is the total SET capacitance from the location of the DJQP feature and $R_n = 25 \text{ k}\Omega$ from the slope of the I - V curve at high bias. Similar measurements for sample B gave $E_c = 222 \mu eV$ and $R_n = 26 \text{ k}\Omega$.

We found that sample B (14 turn inductor) was better matched to the coaxial line, with near perfect matching at $R_d = 20 \text{ k}\Omega$. With the SET biased near the center of the gap ($R_d \gg 1 \text{ M}\Omega$), virtually all the input signal is expected to be reflected. This expectation is in agreement with the data for sample B in the right inset of the Fig. 3, which shows the power P_r reflected by the tank circuit for different R_d . The top curve, which indicates P_r for $R_d \gg 1 \text{ M}\Omega$, has no dip in P_r at resonance, only a background slope due to details of the rf setup. The reflection coefficient Γ shown in Fig. 3 is obtained from the data in the right inset. We assume $\Gamma = 1$ for the largest R_d and, using the top curve as a reference, calculate Γ at different R_d by taking the difference between the other curves and the reference. Virtually identical results are obtained by fitting a line to the background slope of the top curve and using the fit as the reference instead.

With decreasing R_d , Γ decreases over two orders of magnitude at resonance, reaching a minimum of $\Gamma = 0.006$ at $R_d = 19.2 \text{ k}\Omega$. Our bandwidth of roughly $50 \text{ MHz} \sim f_0/Q$ is roughly three times larger than that for measurements with similar Q but lower resonant frequency.^{10,11} From the ratio of Γ at resonance for any two different R_d , and the expressions for Γ , Z_{in} and f_0 given above, we calculate $Q \approx 20$, $L \approx 170 \text{ nH}$ and $C_p \approx 0.17 \text{ pF}$ for which the optimal $R_d = 20 \text{ k}\Omega$. To compare with a commercial inductor, we fabricated a low-impedance sample with $R_n = 13 \text{ k}\Omega$ and coupled it to the coaxial cable through a Panasonic ELJ 82 nH chip inductor. P_r for this sample, for which $f_0 = 975 \text{ MHz}$ and the optimal $R_d = 11 \text{ k}\Omega$, is shown in the left inset of Fig. 3. We estimate $C_p \approx 0.34 \text{ pF}$; the relatively large value of C_p prevents matching to larger R_d . Furthermore, a dip in P_r of about 11 dB appears at resonance for very large R_d , indicating that only about 8% of the input power is reflected. The other 92% is lost to dissipative processes

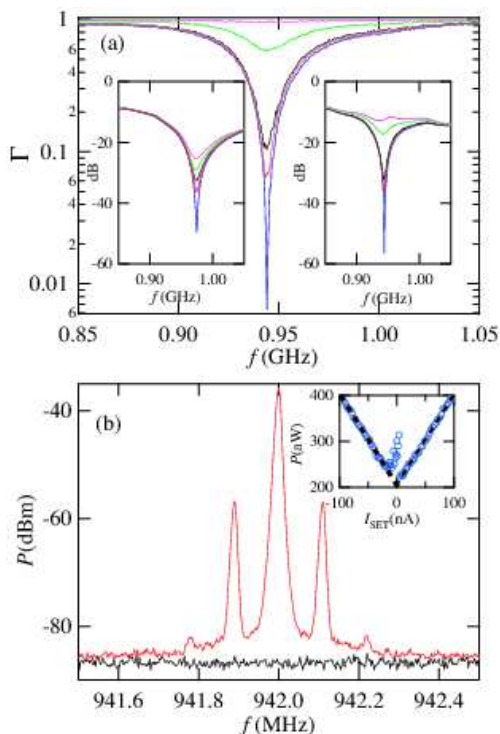


FIG. 3: (a) Γ versus frequency for sample B for different R_d as determined from lockin measurements of G_d . Top to bottom: center of the gap (pink), $R_d = 40$ k Ω (green), 28.2 k Ω (black), 22.2 k Ω (red), 19.2 k Ω (blue). The inset shows reflected power P_r versus frequency for the low impedance SET and Panasonic chip inductor (left) and for sample B (right). Left inset, top to bottom: center of the gap (pink), $R_d = 37$ k Ω (green), 21 k Ω (black), 17.8 k Ω (red), 12 k Ω (blue). Right inset, top to bottom: center of the gap (pink), $R_d = 40$ k Ω (green), 28.2 k Ω (black), 22.2 k Ω (red), 19.2 k Ω (blue). (b) Power spectrum of the RF-SSET output for a 110 kHz 0.01e rms excitation. The lower line is the noise floor with no rf signal applied on the SET. Inset: total system noise at f_0 versus the dc SET current in the absence of applied rf power.

in the matching network.¹⁸

Response of our RF-SSETs to a charge excitation was measured with a spectrum analyzer; typical data are shown in Fig. 3(b). The charge sensitivity δq is determined from the rms charge excitation amplitude q_0 and the signal-to-noise ratio in dB (SNR) of a sideband from $\delta q = (q_0/\sqrt{2\text{BW}})10^{-\text{SNR}/20}$ where BW is the measurement bandwidth. The best charge sensitivity for sample B is $\delta q = 2.4 \times 10^{-6} e/\sqrt{\text{Hz}}$, about three times better than that achieved with a lossy LC network and the same rf setup.¹⁷ We calibrated our system noise temperature for sample B by measuring the total noise power versus the dc SET current I (Fig. 3(b), inset). At higher bias, the noise varies linearly with I due to the SET shot noise.¹¹ The contribution from the HEMT amplifier is determined by the crossing point of the two fitting curves at $I = 0$. We obtain an amplifier noise power $P_n = 210$ aW for a measurement bandwidth $\text{BW} = 3$ MHz, giving a noise temperature $T_n = \frac{P_n}{\text{BW}k_B} = 5.3$ K. The uncoupled energy sensitivity of sample B is $\delta\varepsilon = \frac{(\delta q)^2}{2C_{\text{SET}}} = 1.9\hbar$, approaching the shot noise limit for the RF-SET.^{8,19} Without the contribution from the cryogenic amplifier we estimate $\delta\varepsilon = 1.2\hbar$. For sample A, we measured similar values of $\delta q = 3.1 \times 10^{-6} e/\sqrt{\text{Hz}}$ and $\delta\varepsilon = 3.1\hbar$.

Embedding the RF-SSET in the on-chip matching network shows potential for studying the shot noise of the SET for either rf or dc biases by making several improvements in our system. First, the R_d for optimal charge sensitivity in sample B was about 35 k Ω (point M in Fig. 2(a)), while near-perfect matching occurred at $R_d = 20$ k Ω . Further improvements in the matching network design should allow us to reduce C_p and increase L for better matching with higher R_d without lowering the resonant frequency. Also, using a HEMT amplifier with lower noise temperature will improve both the charge and uncoupled energy sensitivity. Finally, improved fabrication techniques for the SET may also lead to a better charge sensitivity.

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¹ P. W. Shor, in *Proceedings of the 35th Annual Symposium on the Foundations of Computer Science*, edited by S. Goldwasser (IEEE Computer Society, Los Alamitos, CA, 1994), pp. 124–134.

² L. K. Grover, *Phys. Rev. Lett.* **79**, 325 (1997).

³ J. M. Elzerman, R. Hanson, L. H. Willems van Beveren, B. Witkamp, L. M. K. Vandersypen, and L. P. Kouwenhoven, *Nature* **430**, 431 (2004).

⁴ J. R. Petta, A. C. Johnson, J. M. Taylor, E. A. Laird, A. Yacoby, M. D. Lukin, C. M. Marcus, M. P. Hanson, and A. C. Gossard, *Science* **309**, 2180 (2005).

⁵ R. G. Knobel and A. N. Cleland, *Nature* **424**, 291 (2003).

⁶ M. D. LaHaye, O. Buu, B. Camarota, and K. C. Schwab,

Science **304**, 74 (2004).

⁷ V. B. Braginsky and F. Ya. Khalili, *Quantum Measurement* (Cambridge University Press, Cambridge, 1992).

⁸ M. H. Devoret and R. J. Schoelkopf, *Nature* **406**, 1039 (2000).

⁹ R. J. Schoelkopf, P. Wahlgren, A. A. Kozhevnikov, P. Delsing, and D. E. Prober, *Science* **280**, 1238 (1998).

¹⁰ A. Aassime, G. Johansson, G. Wendin, R. J. Schoelkopf, and P. Delsing, *Phys. Rev. Lett.* **86**, 3376 (2001).

¹¹ A. Aassime, D. Gunnarsson, K. Bladh, P. Delsing, and R. Schoelkopf, *Appl. Phys. Lett.* **79**, 4031 (2001).

¹² H. Brenning, S. Kafanov, T. Duty, S. Kubatkin, and P. Delsing, *J. Appl. Phys.* **100**, 114321 (2006).

¹³ A. A. Clerk, S. M. Girvin, A. K. Nguyen, and A. D. Stone, *Phys. Rev. Lett.* **89**, 176804 (2002).

- ¹⁴ Yu. Makhlin, G. Schön, and A. Shnirman, *Rev. Mod. Phys.* **73**, 357 (2001).
- ¹⁵ P. L. D. Abrie, *Design of RF and Microwave Amplifiers and Oscillators* (Artech House, Boston, 2000).
- ¹⁶ T. R. Stevenson, F. A. Pellerano, C. M. Stahle, K. Aidala, and R. J. Schoelkopf, *Appl. Phys. Lett.* **80**, 3012 (2002).
- ¹⁷ M. Thalakulam, Z. Ji, and A. J. Rimberg, *Phys. Rev. Lett.* **93**, 066804 (2004).
- ¹⁸ L. Roschier, P. Hakonen, K. Bladh, P. Delsing, K. W. Lehnert, L. Spietz, and R. J. Schoelkopf, *J. Appl. Phys.* **95**, 1274 (2004).
- ¹⁹ A. N. Korotkov and M. A. Paalanen, *Appl. Phys. Lett.* **74**, 4052 (1999).